

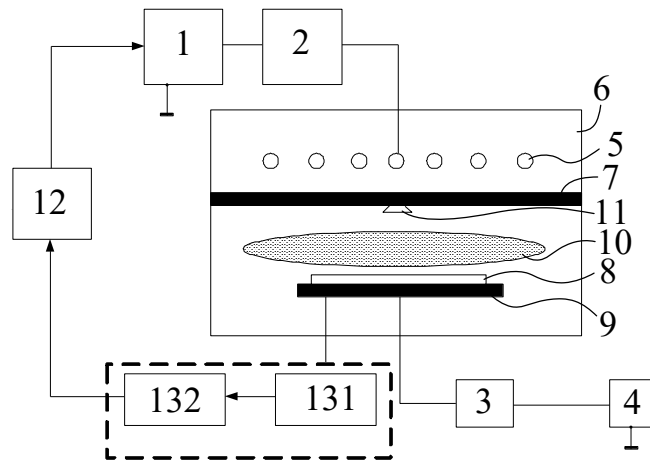


FIG. 1

After the upper electrode assembly excites the process gas in the process chamber to form the plasma, detect the bias voltage value on the upper surface of the chuck in real-time

S1

Calculate the difference between the bias voltage value and the target bias voltage value, and when the difference is greater than the preset threshold, adjust the output power value of the upper electrode assembly according to the difference until the difference is less than or equal to the preset threshold

S2

FIG. 2